



IN THE UNITED STATES PATENTS AND TRADEMARK OFFICE

1763  
K-1984

Applicant : Yasumi Sago et al.

Title : ELECRO-STATIC CHUCKING MECHANISM AND SURFACE PROCESSING APPARATUS

Serial No. : 09/879,934

Filed : June 14, 2001

Group Art Unit : 1763

Examiner : Ram N. Kackar

Hon. Director of Patents and Trademarks  
Washington. D. C. 20231

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AMENDMENT

Sir:

In response to the Office Action of August 20, 2002, please amend the application, as follows:

IN THE SPECIFICATION

Delete paragraph 0002, and add, as follows:

[0002] The electro-static chucking technique is widely used for automatically holding location of an object without damage. Especially, various kinds of surface processing apparatuses utilize the electro-static chucking technique to hold a substrate as the object at a certain position. The electro-static chucking mechanism usually comprises an ESC stage on which the object is chucked, and a chucking power source to apply voltage to the ESC stage for chucking the object. The ESC stage is roughly composed of a main body, a dielectric block fixed with the main body, and a couple of chucking electrodes provided within the dielectric block. Static